#### **Chapter 4 Pressure Measurement**

#### **Contents**

- Introduction
- Absolute pressure, Gauge pressure & differential pressure
- Pressure calibration
- Examples of pressure transducers
- Pressure measurement in fluid mechanics





# What is pressure?

- In mechanics, pressure is force per unit area, i.e., P = dF/dA (in a general sense, it is a type of compressive stress.)
- In hydraulics, pressure is specific weight times height , i.e.,  $\Delta P = \rho g \Delta h$ .

(Pressure is a local flow property and is position-dependent)

- In kinetics, pressure is molecular kinetic energy per unit volume, i.e., P = 2 KE / 3 V
- In thermodynamics, pressure is the work per unit volume, i.e.,
  - $P = (\delta Work + \delta Loss) / dV$



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#### **Phenomena observations**

For fluid at rest,

- Pressure measurements are usually expressed in indirect means, e.g., a column of fluid.
- Pressure is the same in all directions at a given point
- Pressure is unaffected by the shape of the confining boundaries. (⇒a great variety of pressure transducers)
- Pressure is transferred undiminished throughout the confined fluid.





### **Units of pressure**

- Commonly used units of pressure:
  - 1 Torr = 1 mmHg

1 Pa (*pascal*) = 1 N/m<sup>2</sup> = 10 dyne/cm<sup>2</sup> (=1.4504 x10<sup>-4</sup> lb<sub>f</sub>/in<sup>2</sup>)

- $1 \text{ psi} = 1 \text{ lb}_{\text{f}}/\text{in}^2$
- 1atm = 14.69595 psi = 760 Torr = 101,325 N/m<sup>2</sup>
  = 29.9213 in. Hg = 760 mmHg = 1.01325 bar
- 1 bar = 10<sup>5</sup> Pa = 14.5053 psi
- $1 \text{ mmH}_2\text{O} = 9.80665 \text{ Pa}$

(standard atmosphere 1atm: 15°C, sea level)



# Absolute & gauge pressure

There are customarily three ways to describe the pressure:

#### 1.Absolute pressure:(P<sub>abs</sub>)

output pressure measured by an ideal vacuum pressure gauges.

#### 2. Gauge Pressure :( $P_g$ )

absolute pressure minus local atmospheric pressure

#### 3. Differential Pressure :

absolute pressure minus any known pressure



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#### **Pressure measuring instruments**

# Three major types of pressure measuring instruments:

- (a) manometer: low range,
- (b) dial gage: middle range,
- (c) electronic transducers: remote, automatic recording

Pender (1997)

Characteristic	Manometer	Dial gage	Electronic transducer
Pressure range	62 Pa-339 kPa	62 Pa-700 MPa	25 Pa-700 MPa
	$(0.25 \text{ in. } \text{H}_2\text{O}-100 \text{ in. } \text{Hg})$	(0.01 - 100,000  psi)	(0.004–100,000 psi)
Accuracy range	0.25 Pa (0.001 in. H <sub>2</sub> O) to	0.066%–5% full scale	0.003%–3% full scale
	2% full scale		
Frequency response	< 10 Hz	< 10 Hz	DC to 1 MHz
Electronic output	No	No	Yes
Temperature range	-62°C to +66°C	-32°C to +54°C	–271°C to +400°C
Media compatibility	Gas	Gas or liquid	Gas or liquid
Cost (U.S.)	\$100-\$2000	\$10-\$3000	\$50-\$10,000

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#### Manometer



Pender (1997)

- Measuring range:
  62 Pa ~ 339kPa
- Accuracy: 0.025% ~ 2% of full scale
- Disadvantages: result is ρ and g-dependent, lack of recording and limited frequency response

Туре	Full scale range	Accuracy range
U-tube	500 Pa-339 kPa	0.25 Pa (0.001 in. H <sub>2</sub> O)-
	(2 in. H <sub>2</sub> O–100 in. Hg)	2% of full scale
Well	1 kPa-339 kPa	0.01% of full scale-2% of
	(4 in. H <sub>2</sub> O–100 in. Hg)	full scale
Inclined	62 Pa-5 kPa	0.025% of full Scale-1% of
	$(0.25 \text{ in. } H_2O-20 \text{ in. } H_2O)$	full scale

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#### **Micromanometer**

- Measuring range: up to 20"H<sub>2</sub>O
- Accuracy: 0.0005"
- Simple
- Disadvantages: sensing by eyes



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#### Manometer for remote use



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#### Range of pressure measurement





# Deadweight gauge calibrator





#### Low Pressure measurement

- For pressure from 1 to 10<sup>-5</sup> mmHg, McLeod vacuum gage is commonly used.
- Uncertainty: Pressure *p* 3~0.5% of reading • lack of continuous out Area A+ -• Based on Boyle's law  $p_i V = p A_t h$  $= (p_i + \gamma h) A_t h$ Plunger Volume  $p_i = \frac{\gamma A_t h^2}{V - A h} \approx \frac{\gamma A_t h^2}{V}$ -Specific veight y (6)  $\{a\}$ Benedict (1984)



### What is pressure transducer ?

Pressure transducers are devices those convert an applied pressure into a sensible signal (electric signal or others) through a sensor (displacement, strain, piezoelectric response...etc.).





#### **Choose a Pressure transducer**

- Common classifications :
  - (a) displacement type (includes diaphragm type)
  - (b) piezoelectric type
  - (c) piezoresistive type
  - (d) capacitance type
  - (e) reluctance type
- The choice of transducer varies greatly depending on many factor like: pressure range, dynamic response, pressure media, dimensional restrictions, budget...etc.



# **Bourdon gage**

Oval cross section

- Simple & robust
- Max. measuring range: 0.6 ~ 10,000bar
- Min. resolution: ~10 Torr
- accuracy: 1~1.6% of F.S.



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Spring

#### Elastic element of pressure transducer



#### Doebelin (1990)

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#### LVDT pressure transducer

- LVDT: Linear Variable Differential Transformer
- Limit frequency response ~ 10Hz



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#### **Electro-optic transducer**

Ref.

photo

diode

LED

Meas.

photo

diode

Pressure

- Infrared LED
- The reference and measurement photodiodes are equally affected by temperature change



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### Diaphragm gage

12

10

- For low- and middle-pressure measuring range: 0.01 ~ 25bar
- min. resolution: ~10<sup>-3</sup> Torr



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# Diaphragm type strain-gage pickup





- For  $y_c/t < 0.25$ , linearity within 0.3%
- Measuring range: 0 10 ~ 3,000 bar.
- Dynamic frequency: DC ~ 10kHz
- Accuracy: ~ 0.1%

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Balance pot



#### **Bellow pressure transducer**





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#### **Piezoelectric transducer**



(Kistler Instrument Corp.)

- Suitable for high-frequencychanging and large pressure measurement, not suitable for low-frequency measurement
- Measuring range
  100mbar ~ 100kpsi.
- Accuracy: 1 ~ 3%
- Resonant frequency:
  0.25 ~ 0.5 MHz
- Temperature range: -200 up to 350°C (error <1%)</li>
- Max. gas temp 2000 °C (for short time)

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#### **Piezoresistive pressure transducer**

- Piezoresistive effect  $\Delta \rho / \rho \sim \Delta L / L$ , where  $\rho$ : resistivity
- Gauge factor[ $(\Delta R/R)/(\Delta L/L)$ ]: 50 ~ 100 (e.g., strain gage ~ 2)
- low cast
- Thermal zero drift
- SMI's chip









#### **Capacitive Pressure Sensors**



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#### **Reluctance type transducer**



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#### Pressure measurements in moving fluid

- Difficulties: (a) sensing small pressure in large pressures, (b)interface with different liquid
- $P_0 = P_s + P_d$ 
  - **P**<sub>0</sub>: total (stagnation) pressure
  - **P**<sub>s</sub>: static pressure
  - **P**<sub>d</sub> : dynamics pressure
- For laminar flow, all pressure are steady, but the pressure are time-dependent for turbulent case. Kilohertz response of pressure transducer is needed for the latter case.



#### Static pressure measurement

- Pressure tap are small circular hole drilled perpendicular to the wall surface for measuring static pressure.
- The corner of the hole should be sharp and squared off.
- The recommended geometries are all from experimental determination.
- The orifice must be burr-free, for burr heights less than 1/30d, errors are less than 1% of  $\rho V^2/2$
- In pipe flows, several taps around the circumference can be made and connected together in ring.



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#### Static pressure measurement



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#### Static pressure measurement



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#### Static pressure tube



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#### Multi-manometer



principle

Recorded by camera





#### **Scanivalve**

Advantage of scanivalve: only one pressure sensor (and also one calibration) is needed

- Mechanical type : range:±70 mbar ~ 34 bar time resolution : 3~5 measurements/s
- Electronic type : range :± 350mbar ~ 7bar time resolution : 10,000 measurements/s (all pressure sensor in one chip
  - + multiplexer-preamplifier.)



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### Total pressure measurement (I)

- Pitot tube since 1732
- Based on Bernoulli equation  $P_0 = P_s + P_d$
- The mechanical leading on the stem is roughly estimated as two times of the dynamic head.
- A total head tube with hemispherical tip will read the total head accurately independent of the size of the orifice opening as long as the yaw is less than 30.





#### Total pressure measurement (II)





#### Dynamic pressure measurement (I)



- Pitot-static tube (or Prandtl tube) is used to measure dynamic pressure and hence flow velocity.
- It should not be used at too low Reynolds numbers or too close to a wall.



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#### **Dynamic pressure measurement (II)**

#### Other operation notes for Pitot-static tube

 Time constant : the response rate for Pitot-static tubes depends on (a) length and diameter of pressure passages and (b) displacement volume of manometer e.g. 1.6 mm-O.D tube: 15~60seconds in air 0.8mm -O.D tube up to 15min in air (standard tubes are usually over 1.6mm O.D)

• Turbulence effect :

the measured pressure in isotropic turbulence is by Chue (1975):  $\rho V^2/2 + \alpha \rho q^2$ where is 1/6 for small scale turbulence and 5/6 for large scale turbulence



#### Surface pressure measurement

- Applications: flow unsteadiness, aerodynamic noise
- pin-holes produce measuring distortion
- piezoelectric film, e.g. Polyvinylidenfluorid PVDF (t ~ 25μm), is flexible and smooth and can be glued directly on the surface of measuring object (Nitsche et al. 1989).



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### Flow direction measurement

- Multi-hole pressure probes are used when both velocity magnitude and direction are to be determined. For applications in need of high spatial resolution, the three -hole probe (or 'cobra' probe can be used. In both pitch and yaw angles are required, the five-hole probe is used.
- The probe is rotated in the flow until the pitch angle is then known.
- Once calibrated, the (three-hole / five-hole) probe also allows the yaw angle to be measured.



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#### **Pressure sensor in Micro-channel**





#### Sound pressure measurement



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#### Sound pressure measurement

- Three filters (or weighting networks): A , B and C. A scale is commonly used.
- Free-field response of a microphone





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#### **References**

- Benedict, R.P "Fundamentals of temperature, pressure, and flow measurements", 3rd Ed., John Wiley & Sons, 1984.
- Bohl, W., "Technische Stroemungslehre", Vogel, 1991
- Chue, S,H, Pressure Probes for fluid measurement, Prog Aerospace Sci ,Vol. 16 147-223, 1975
- Dally, J.W., Riley, W.F. & McConnell, K.G., Instrumentation for Engineering Measurements, 2nd Ed., John Wiley & Sons, 1993.
- Doebelin, E.D "Measurement systems", 4th Ed., McGraw-Hill, 1990
- Ewald,,B. "Messtechink II, TH Darmstadt, 1991
- Goldstein, RJ, "Fluid Mechanics Measurements", 2nd Ed., Hemisphere, 1996
- Ho, C.-M. & Tai, Y.-C., Micro-Electro-Mechanical-Systems (MEMS) and Fluid Flows, Annu. Rev. Fluid Mech., Vol. 30, pp.579–612, 1998
- Pender, G.A., Measuring pressure in electronic system, in Azar, K. Editor, chapter 6, Thermal measurements in Electronic Cooling, CRC Press, 1997.
- Pong KC, Ho CM, Liu J, Tai YC., Non-linear pressure distribution in uniform microchannels, *ASME FED* 197, pp.51–56. 1994.
- Ras W.H, Pope "Low-speed wind tunnel testing," John Wiley & Sons, 1984
- Tropea, C, "Einfuehrung in die Stroemungsmechanik," LSTM-Erlangen, 1994
- Wuest, W., "Stromungsmebtechnik", Friedr. Vieweg & Sohn, 1969

